007 1 9 2001 & Docket Nov. L&L-10078 0460

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Alfred Kersch et al.

Applic. No.

09/939,330

Filed

August 24, 2001

Title

Method of Producing a Ferroelectric Solid-State Layer Using

an Auxiliary Substance

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner of Patents and Trademarks, Washington, D.C. 20231

Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

Japanese Patent Abstract JP 03 197 394 A (Ogaki et al.), dated August 28, 1991;

Japanese Patent Abstract JP 04 137 532 A (Horioka et al.), dated May 12, 1992;

J.L. Archer et al.: "Chemical Vapor Deposition Of Single-Crystal Metal Oxides. II. Encapsulation Of Polycrystalline Conductors In Single-Crystal Ferrite", J. Phys. Chem. Solids, Suppl. 1967, No. 1, pp. 337-340;

Jing Zhao et al.: "Low Pressure Organometallic Chemical Vapor Deposition Of High -T_C Superconducting YBa₂Cu₃O_{7-δ} Films", Solid State Communications, Vol. 69, No. 2, 1989, pp. 187-189;

Shogo Matsubara et al.: "Preparation of epitaxial ABO3 perovskite-type oxide thin films on a (100)MgAl₂O₄/Si substrate", J. Appl. Phys. Vol. 66, No. 12, December 15, 1989,

pp. 5826-5832;

Clive D. Chandler et al.: "Chemical Aspects of Solution Routes to Perovskite-Phase

Mixed-Metal Oxides from Metal-Organic Precursors", Chem. Rev. 1993, No. 93, pp.

1205-1241;

D. Saulys et al.: "An examination of the surface decomposition chemistry of lithium niobate precursors under high vacuum conditions", Journal of Crystal Growth, No. 217,

2000, pp. 287-301;

Y. Gao et al.: "Effects of precursors and substrate materials on microstructure, dielectric

properties, and step coverage of (Ba,Sr)TiO₃ films grown by metalorganic vapor

deposition", Journal of Applied Physics, Vol. 87, No. 1, January 1, 2000, pp. 124-132.

If no translation of pertinent portions of any foreign language patents or publications mentioned above is included with the aforementioned copies of those applications, patents and/or publications, it is because no existing translation is readily available to the applicant.

Respectfully submitted,

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